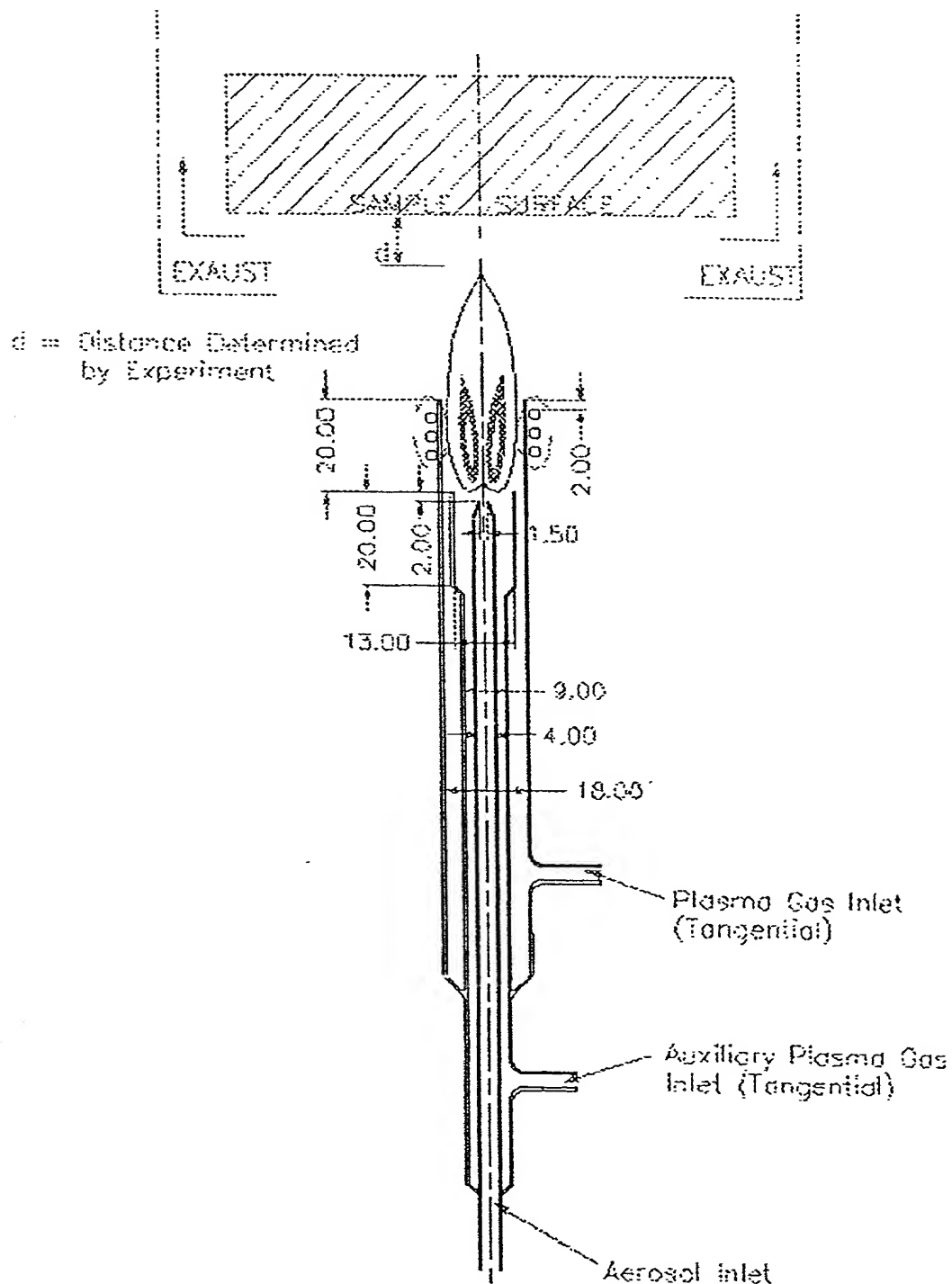
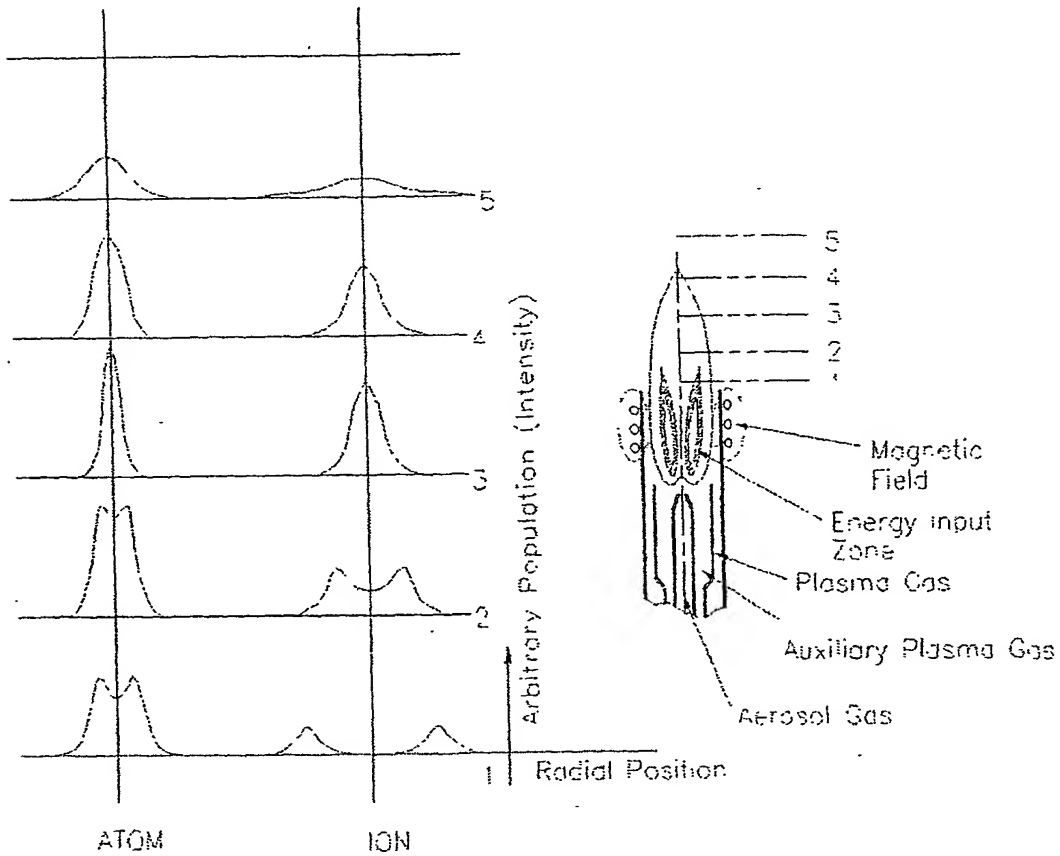


Fig 1: ICP Torch



(all measurements are in millimeters)

Fig. 2: Atom and Ion Distribution in the ICP



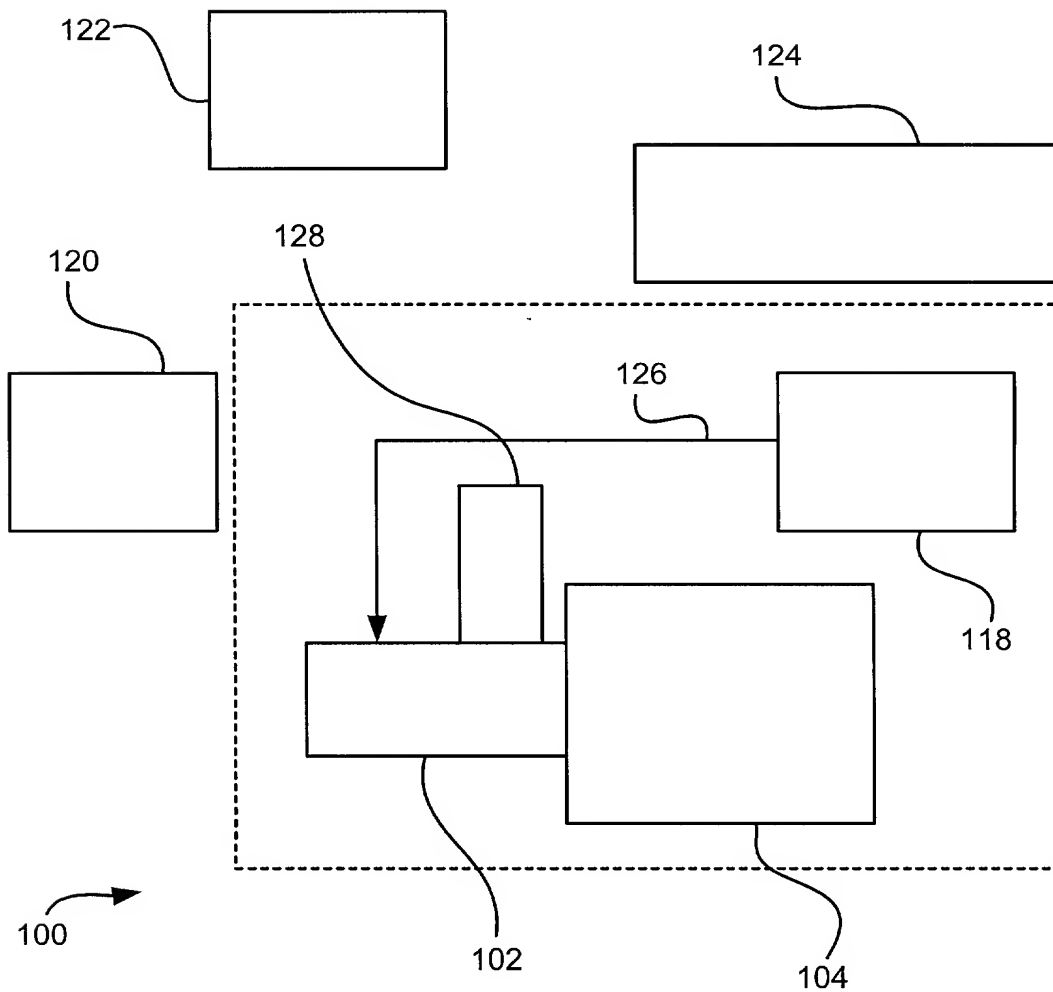


FIG. 3

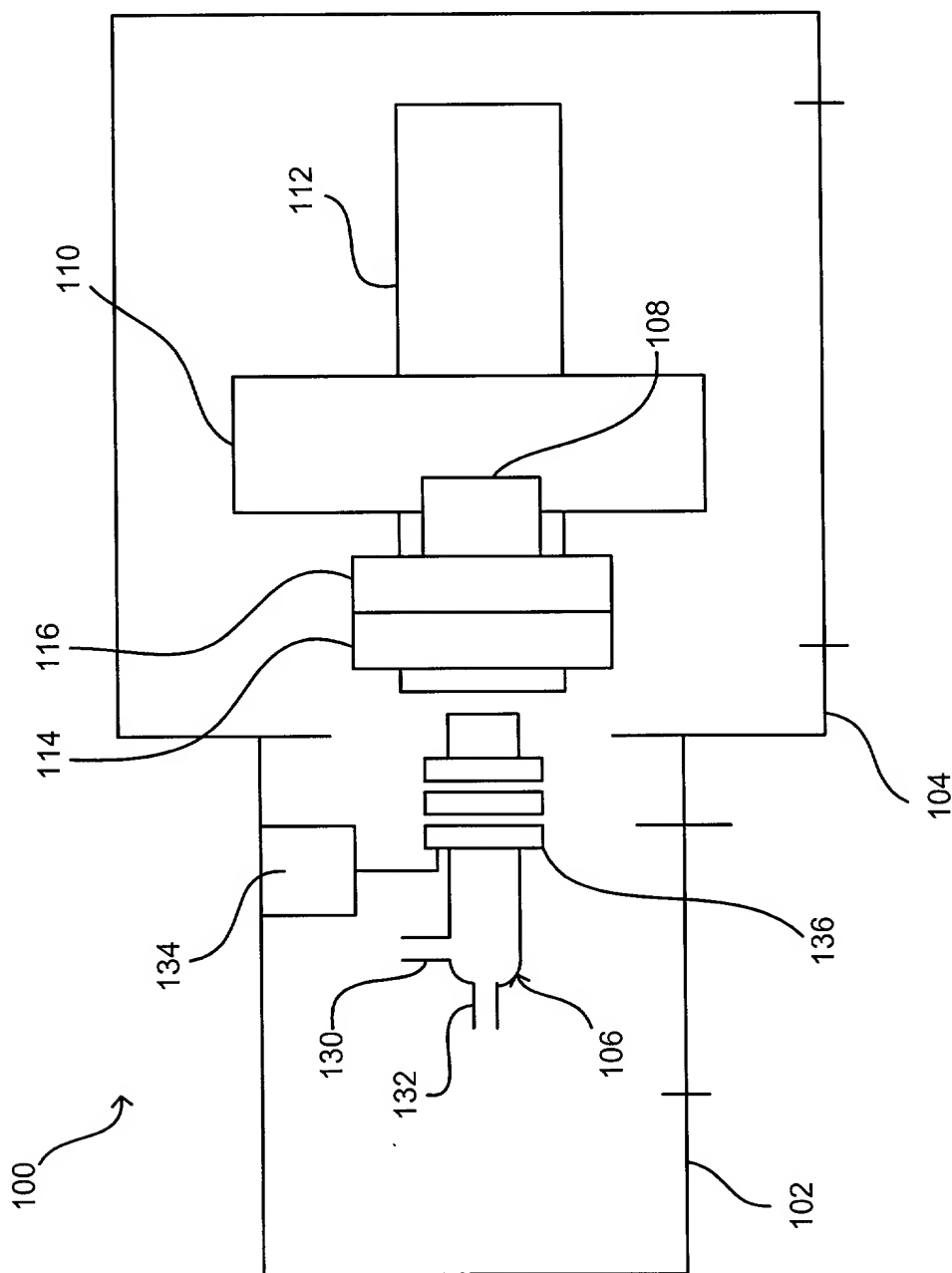


FIG. 4

FIG. 4 of 5602007

Title: APPARATUS AND METHOD FOR ATMOSPHERIC PRESSURE REACTIVE
ATOM PLASMA PROCESSING FOR SHAPING OF DAMAGE FREE SURFACES

Docket No.: BEAS-01000US1

Applicant(s): Jeffrey W. Carr

Appl. No.: Unknown

Attorney: Jason D. Lohr

Filed: Herewith

Phone: (415) 362-3800

Express Mail No : EL622697655US

Sheet 5 of 10

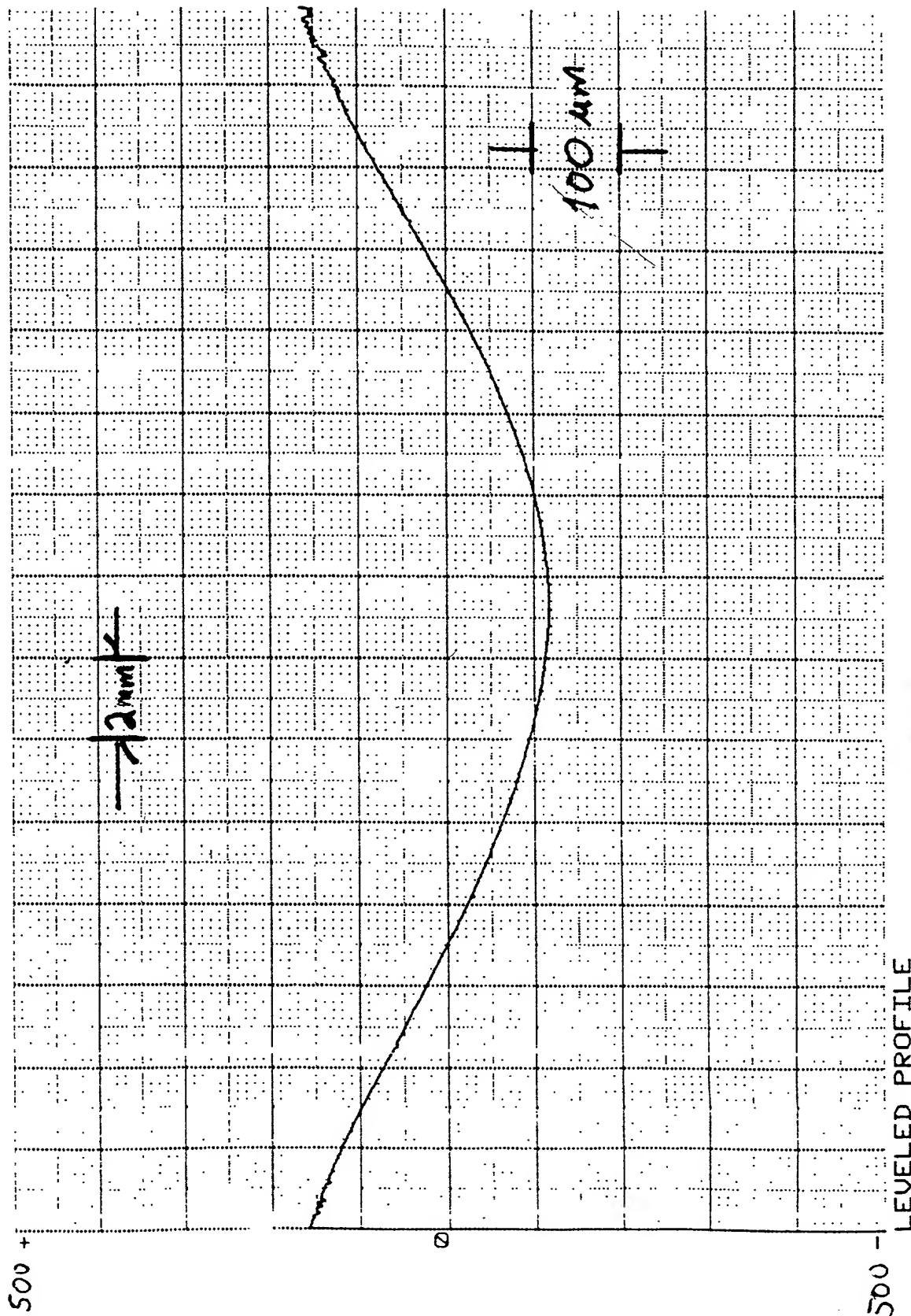


Fig 5

10002035.110101

Title: APPARATUS AND METHOD FOR ATMOSPHERIC PRESSURE REACTIVE
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Sheet 6 of 10

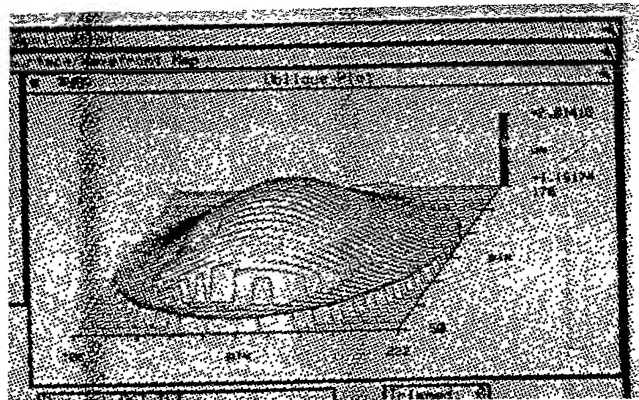
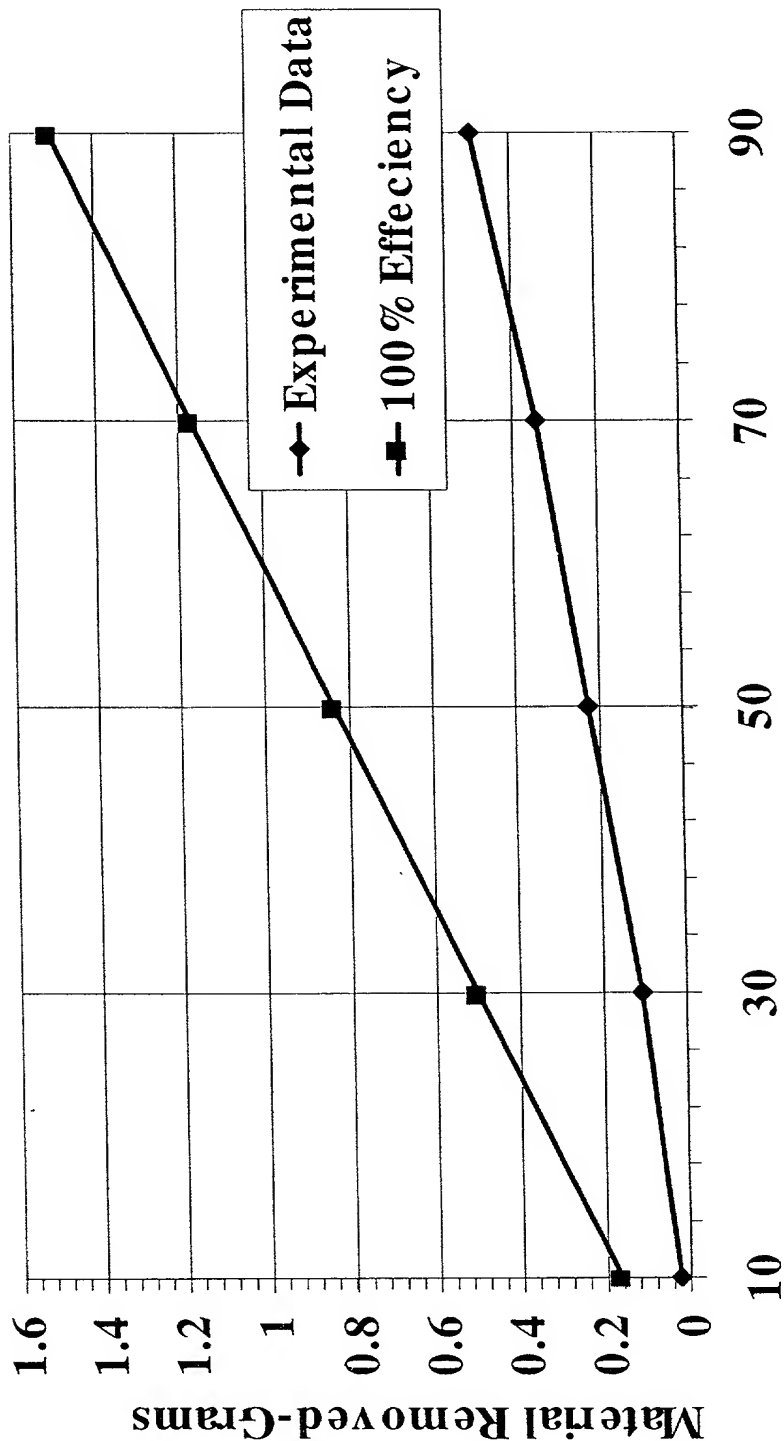


Fig 6

10000035-110101

Effect of Reaction Gas Flow Rate on Removal



Reaction Gas Concentration

Fig 7

Effect of Distance from Plasma

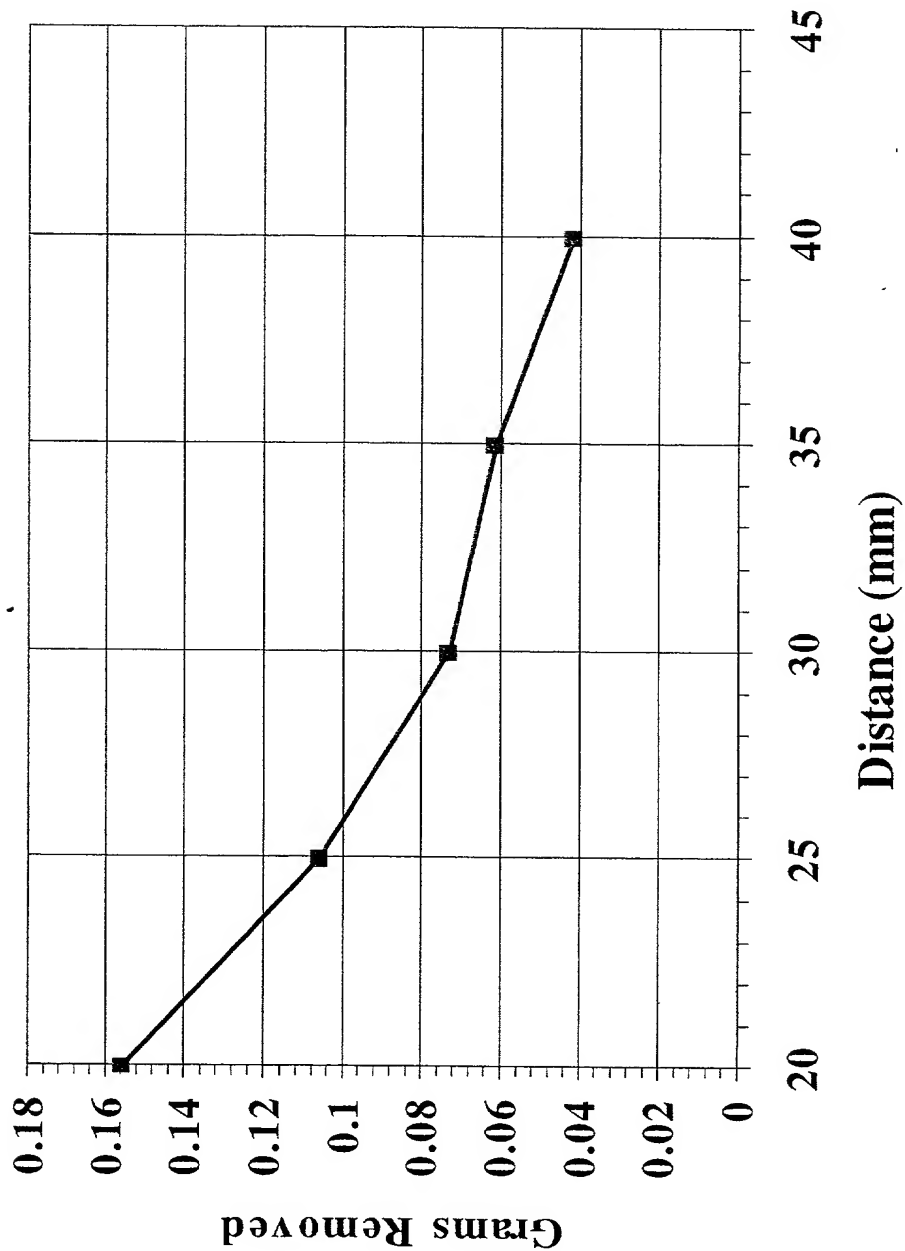


Fig 8

Effect of Reaction Gas Flow Rate on Efficiency

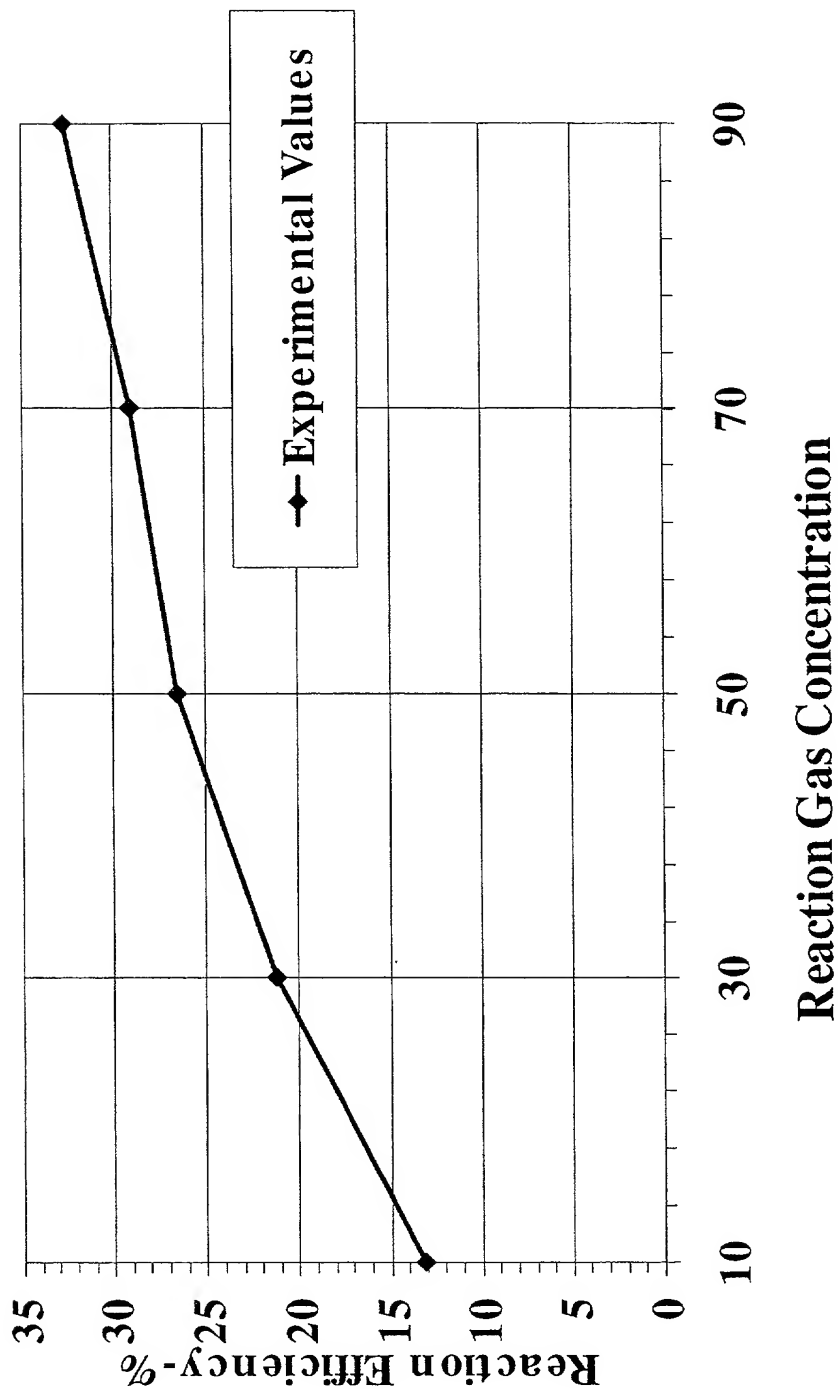


Fig 9

Effect of Distance from Plasma on Efficiency

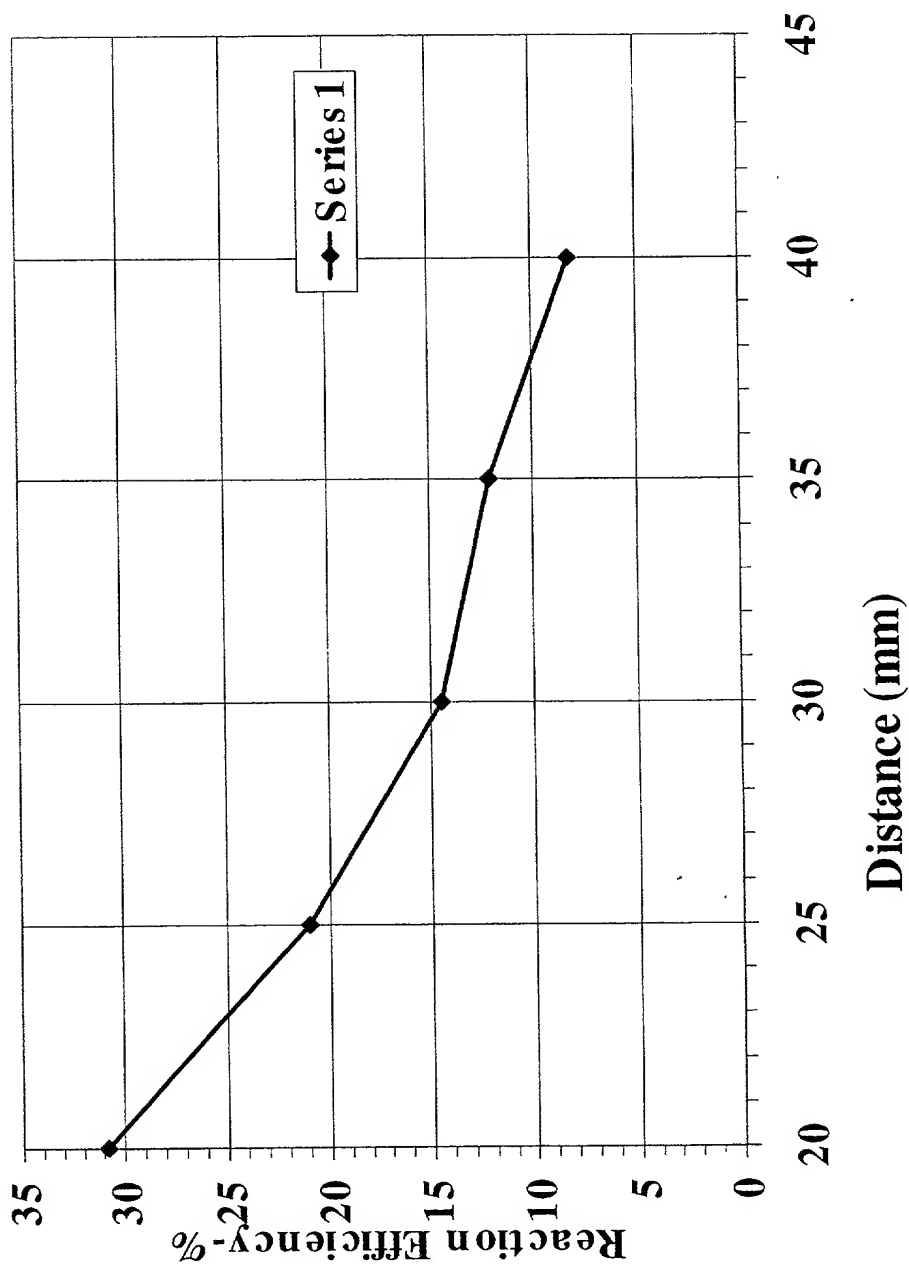


Fig 10